



MEMS Magnetic Devices and Applications

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Message from the Guest Editors

With the development of microelectronics technology, people have developed micro magnetic devices in various aspects such as actuators, sensors, and energy harvesters by using micro-nano processing technology, and these have been widely used in scientific research production and various aspects of society.

To promote the development of MEMS magnetic devices and strengthen academic communication and innovations, we are launching this Special Issue titled "MEMS Magnetic Devices and Applications", which will focus on new magnetic devices, such as actuators, sensors, and energy harvesters and their design, simulation, and fabrication, the micro/nano fabrication of magnetic materials including metals, organic compounds, alloys, 2D materials, and any materials used in magnetic sensors, as well as the application of MEMS magnetic devices, such as nano magnetic robot, current detecting, navigation, bio-detecting, microinductance, nondestructive testing, micro energy harvester, etc. We hope that this Special Issue will play a beneficial role in promoting the future research of MEMS magnetic devices and applications.





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Editor-in-Chief

Message from the Editor-in-Chief

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